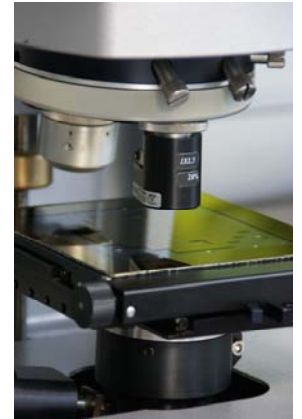


**Manufacturer**  
Veeco Instruments

**Model**  
Wyko NT1100



## Interferometer



### Surface topography measurements

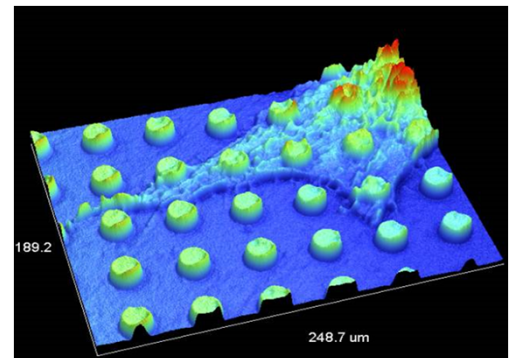
The optical profilometer Wyko NT1100 provides high-resolution 2D and 3D surface measurements without contact, from sub-nanometer roughness to millimeter-high steps for the characterization of surfaces.

It allows:

- Measuring features from 50 nm to 1 mm in VSI mode
- Roughness measurements
- 3D image generation

### Technical specifications

- Measurement modes:
  - Vertical Shift Interferometry (VSI), used for measuring features in the range of 140 nm to several  $\mu\text{m}$ .
- Automated stitching stage for large area coverage.
- Light Source: tungsten halogen lamp
- Objective lenses : Michelson (5.0X) and Mirau (50X).
- Field-of-View (FOV) lenses: 0.5, 1.0 and 2.0.
- CCD camera to transfer the images to a computer for analysis.
- Performance:
  - Vertical measurement range: 0.1 nm to 1 mm
  - Vertical resolution:  $< 1 \text{ \AA}$  (Ra)
  - Vertical scan speed up to  $7.2 \mu\text{m}/\text{sec}$
  - Lateral spatial sampling 0.08 to  $13.1 \mu\text{m}$
  - Field-of-View  $0.47 \times 0.62 \text{ mm}^2$  to  $1.88 \times 2.47 \text{ mm}^2$  (larger areas with data stitching mode)



[www.ibeccbarcelona.eu/corefacilities](http://www.ibeccbarcelona.eu/corefacilities)

[microfab@ibeccbarcelona.eu](mailto:microfab@ibeccbarcelona.eu)

## Interferometer

### Available software:

Vision32®

- Enables advanced calculations of various surface parameters and image processing

